



Electromagnetic characterization of materials for the CLIC Damping Rings and high frequency issues

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Acknowledgements

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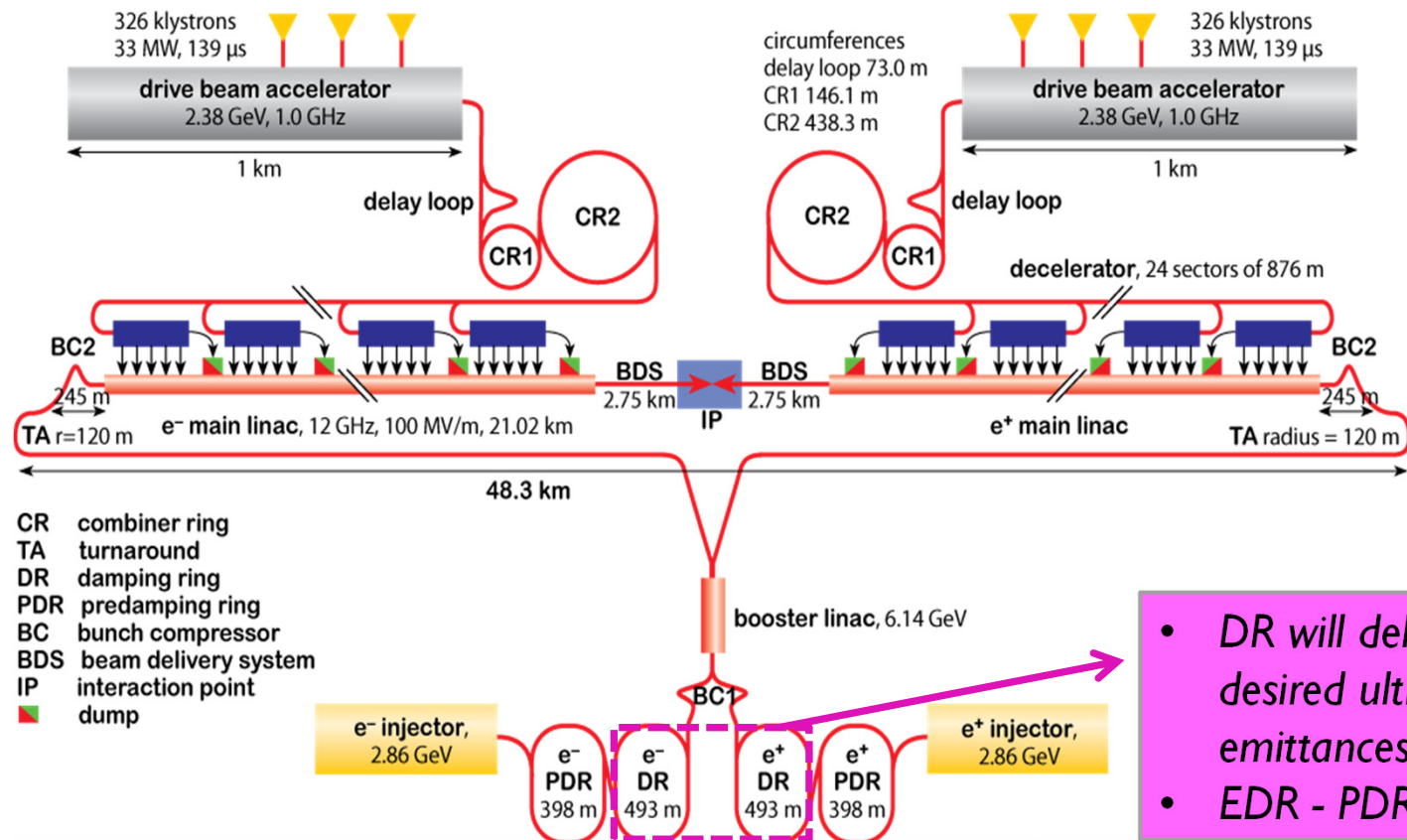
Outline

- ▶ Introduction
- ▶ Motivation
- ▶ Experimental method- simulations
- ▶ First results- testing simulations
- ▶ Conclusions- future planning- challenges

Introduction (I)

CLIC: a future multi-TeV e^+e^- collider

- ▶ Compact Linear Collider (CLIC)
- ▶ Allows the exploration of a new energy regime, in the multi-TeV range beyond the capabilities of today's particle accelerators



- DR will deliver the desired ultra low emittances
- EDR - PDR

Introduction (II)

Damping Rings

CLIC DR parameters

Parameters	CLIC@3TeV
Energy [GeV]	2.86
Circumference [m]	427.5
Energy loss/turn [MeV]	4.0
RF voltage [MV]	5.1
Stationary phase [°]	51
Momentum compaction factor	1.3e-4
Damping time x/s [ms]	2/1
Number of dipoles/wigglers	100/52
Dipole/wiggler field [T]	1.0/2.5
Bend gradient [1/m ²]	-1.1
Bunch population [10 ⁹]	4.1
Horizontal normalized emittance [nm.rad]	456
Vertical normalized emittance [nm.rad]	4.8
Bunch length [mm]	1.8
Longitudinal normalized emittance [keV.m]	6.0

- Small emittance, short bunch length and high current
- Rise to collective effects which can degrade the beam quality

Introduction (III)

Collective effects

- ▶ Represent phenomena describing the evolution of a particle beam under the effect of self-induced forces
- ▶ Could lead to instabilities, tune shift, beam loss and emittance growth
- ▶ Determine the performance of an accelerator (by limiting the beam intensity or degrading beam quality)
- ▶ Study to ensure safe operation under nominal conditions
- ▶ Focus on impedance

To suppress some of those effects, coating will be used

- Positron Damping Ring (PDR): electron-cloud effects → amorphous carbon (aC)
- Electron Damping Ring (EDR): fast ion instabilities → need for ultra-low vacuum pressure → Non-Evaporable Getter (NEG)

Introduction (IV)

Tools

▶ HEADTAIL code

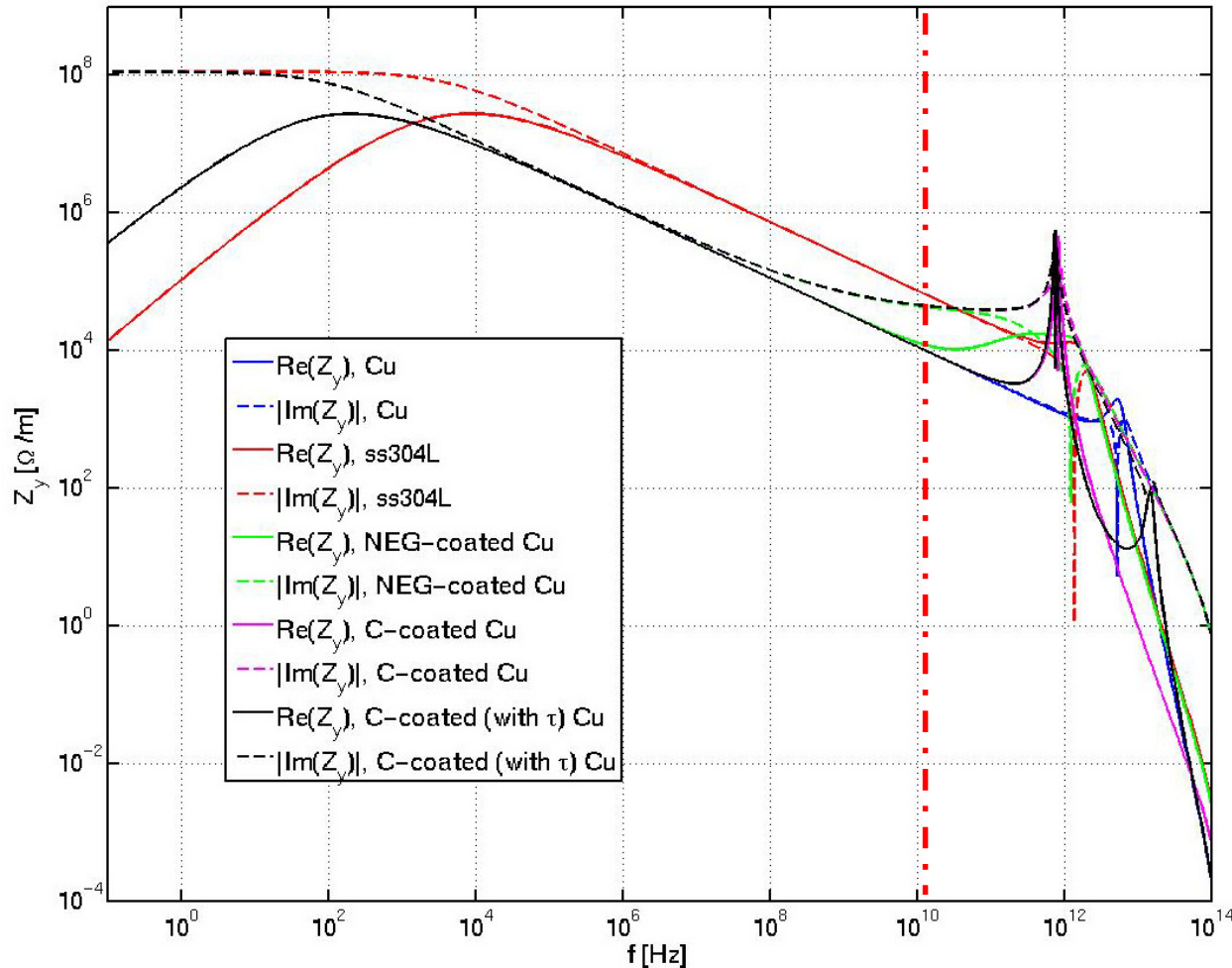
- ▶ Simulates single bunch collective phenomena associated with impedances (or electron cloud)
- ▶ Computes the evolution of the bunch centroid as a function of time over an adjustable number of turns

▶ ImpedanceWake2D

- ▶ Computes the longitudinal and transverse wake functions of multilayer structures, cylindrical or flat

▶ CST Microwave Studio

Resistive Wall Vertical Impedance: Various options for the wigglers pipe



⇒ a-C necessary for e^- cloud mitigation

⇒ NEG for good vacuum

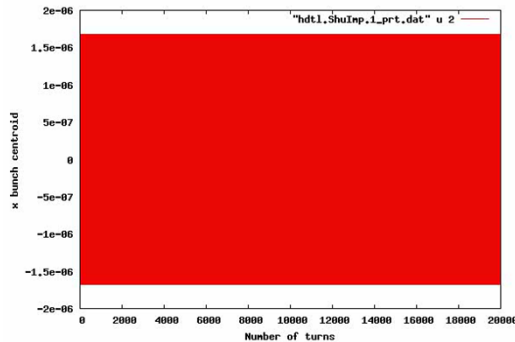
⇒ Coating is “transparent” up to ~ 10 GHz

⇒ But at higher frequencies some narrow peaks appear

⇒ Important to define the contribution of the resistive wall

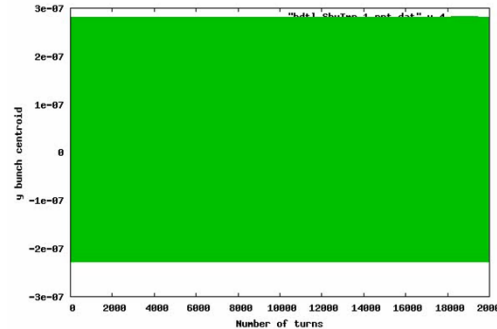
Single bunch simulations to define the instability thresholds

x bunch centroid position



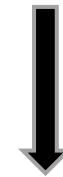
Number of turns

y bunch centroid



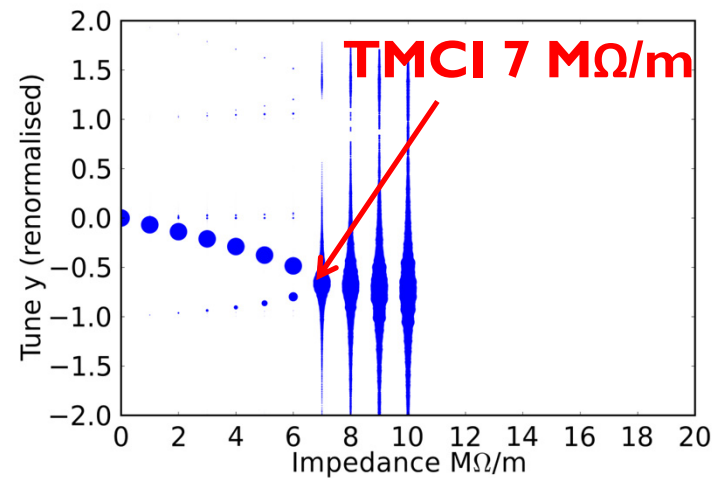
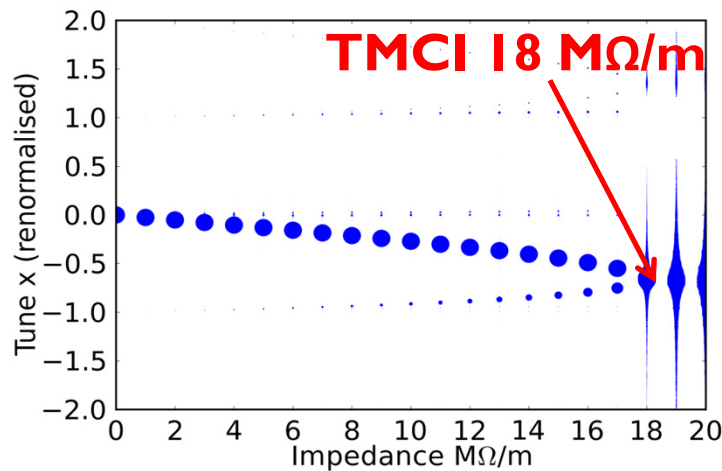
Number of turns

HEADTAIL output:
Position of the centroid
over the number of turns



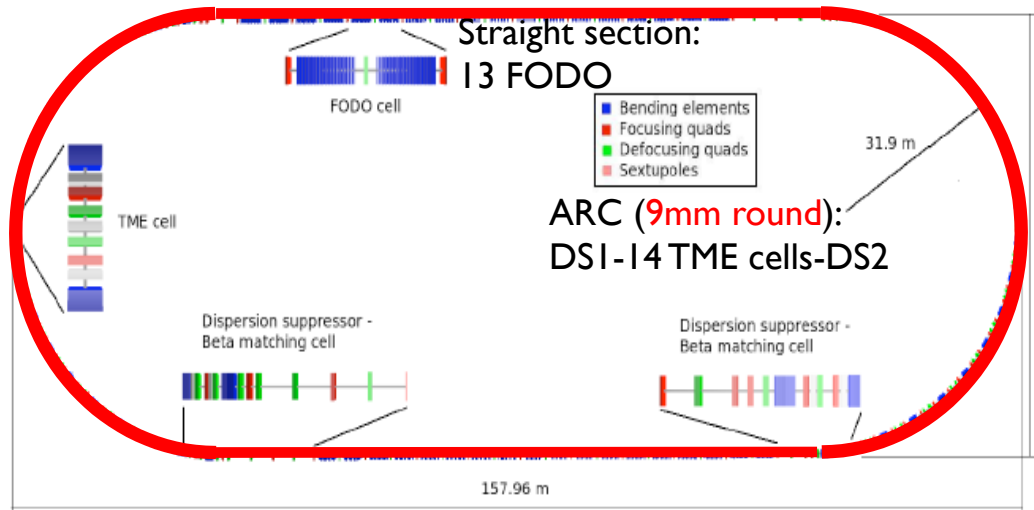
FFT/
Sussix

Mode spectrum of the horizontal and vertical coherent motion as a function of impedance



For zero chromaticity, the impedance budget is estimated at 7 MΩ/m

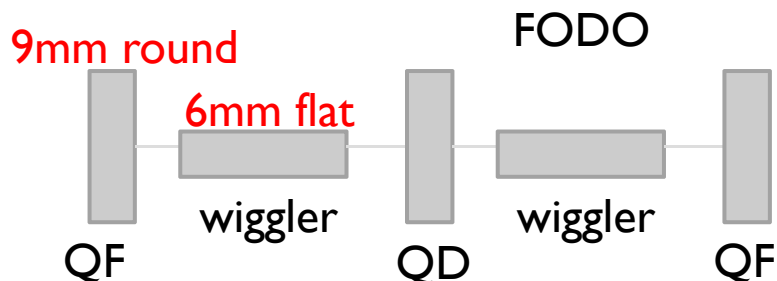
Estimating the machine impedance budget with a 4-kick approximation



- A uniform coating of NEG, $2\mu\text{m}$ thickness, ($\sigma=10^6 \text{ S/m}$) was assumed around the ring made from stainless steel
- The contributions from the resistive wall of the beam chamber were singled out for both the arc dipoles and the wigglers

1 kick → broadband resonator ($S_{\text{kick}}=1\text{m}$)

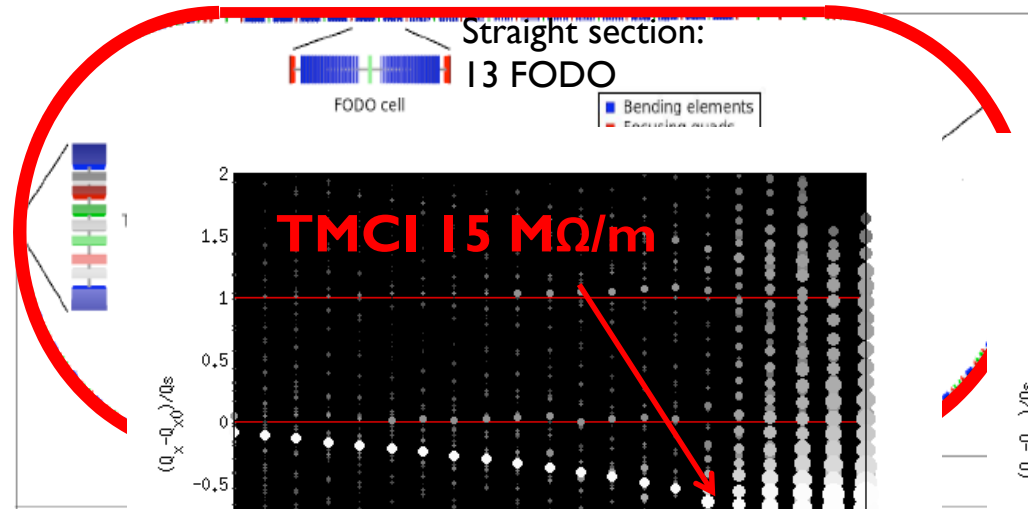
2 kick → arc ($L=270.2\text{m}$, 9mm , round, $\langle b_x \rangle=2.976\text{m}$, $\langle b_y \rangle=8.829\text{m}$, $S_{\text{kick}}=150\text{m}$)



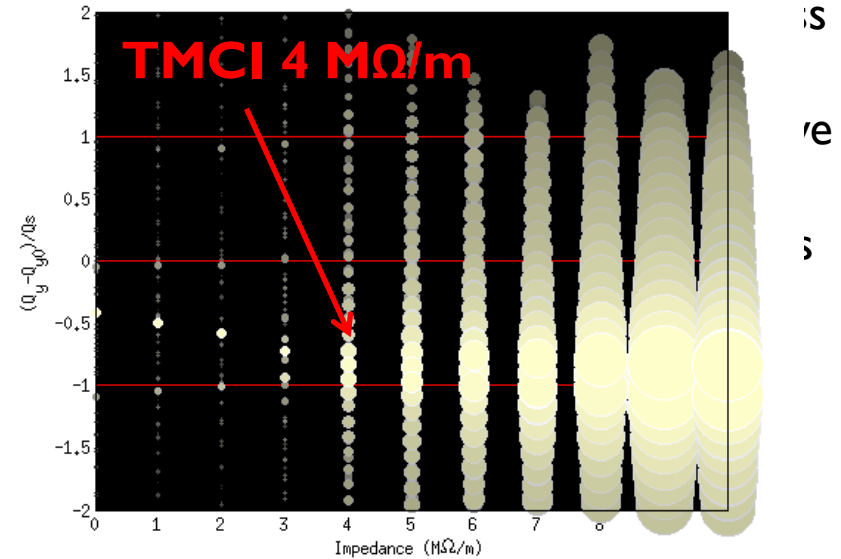
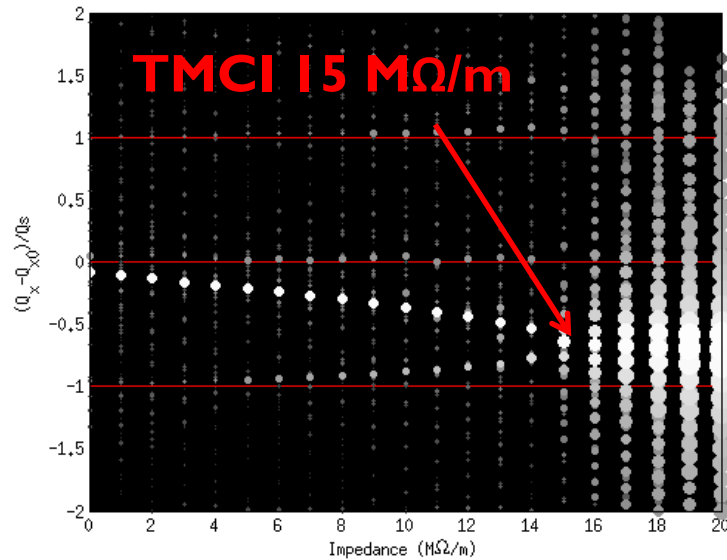
3 kick → wigglers ($L=104\text{m}$, 6mm , flat, $\langle b_x \rangle=4.200\text{m}$, $\langle b_y \rangle=9.839\text{m}$, $S_{\text{kick}}=41.3\text{m}$)

4 kick → rest of the FODO ($L=53.3\text{m}$, 9mm , round, $\langle b_x \rangle=5.665\text{m}$, $\langle b_y \rangle=8.582\text{m}$, $S_{\text{kick}}=39.2\text{m}$)

Estimating the machine impedance budget with a 4-kick approximation



- A uniform coating of NEG, 2 μ m thickness ($\sigma=10^6$ S/m) was assumed

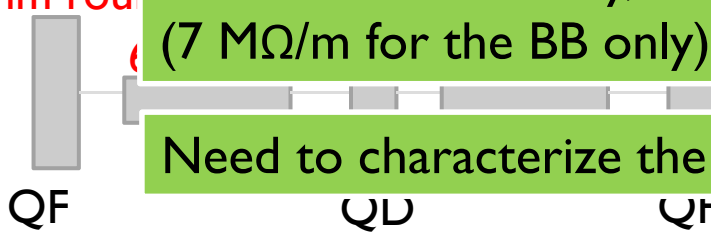


1 kick
2 kick
<by>=ξ

9mm rou

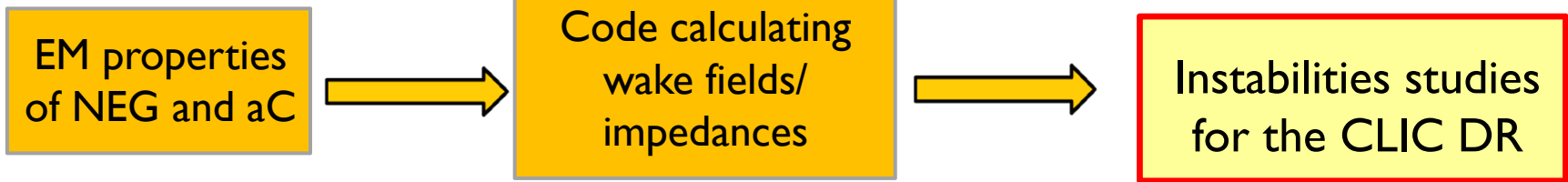
For zero chromaticity, the impedance budget is estimated at 4 MΩ/m (7 MΩ/m for the BB only)

Need to characterize the properties of NEG



round, $\sigma_x = 0.005$ m, $\sigma_y = 0.002$ m, $\sigma_{kick} = 0.2$ m

Motivation



- Need to characterize the properties of the coating materials at high frequencies (CLIC), i.e. 500 GHz

- Characterize the electrical conductivity of *NEG*

- Combination of experimental method and EM simulations

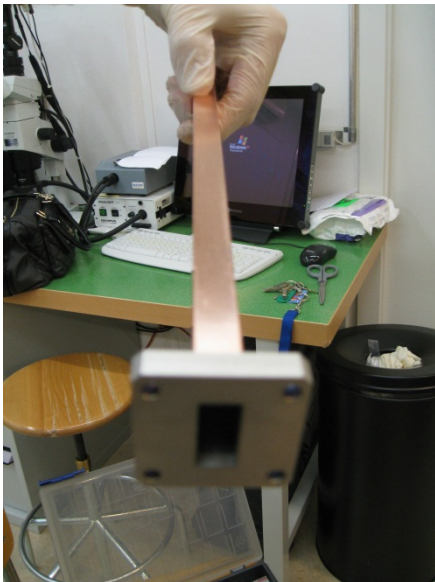
TiZrV coating



Experimental Method (I)

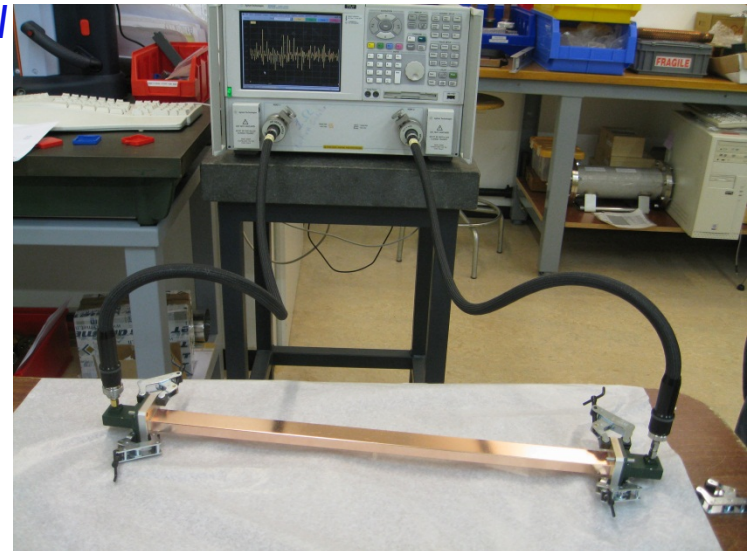
▶ Waveguide Method

- ▶ First tested at low frequencies, from 9-12 GHz
- ▶ Use of a standard X-band waveguide, 50 cm length
- ▶ Network analyzer
- ▶ Measurement of the transmission coefficient S_{21}



*X band Cu waveguide
of 50 cm length*

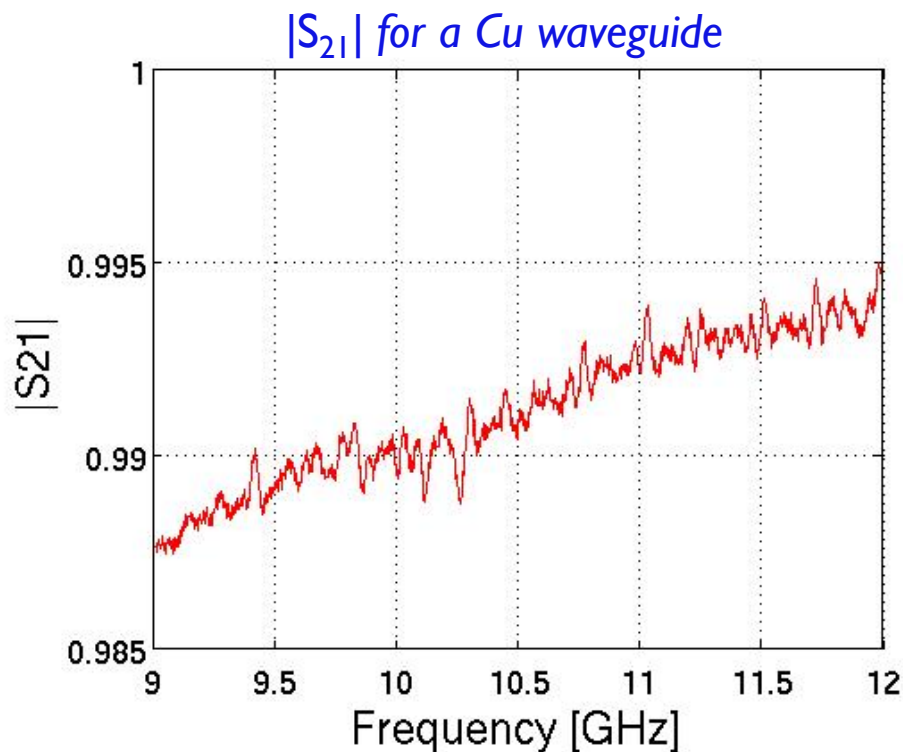
*Experimental
setup*



Experimental Method (II)

▶ Copper waveguide

- ▶ First test: a pure copper (Cu) X band waveguide
- ▶ Measure the S_{21} from 9-12 GHz



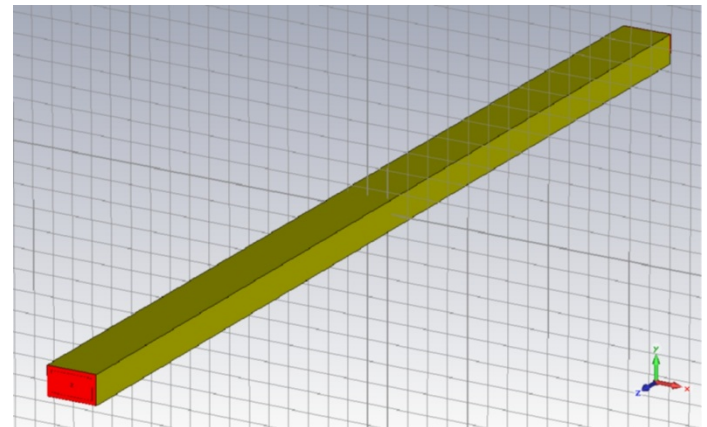
- Signals traveling in the waveguide experience loss due to the conductor resistance
- S_{21} is related to the loss suffered in the transmission from one port to the other
- Cu is a very good conductor and the losses are small
- S_{21} is related to the material conductivity

3D EM Simulations (I)

CST Microwave Studio

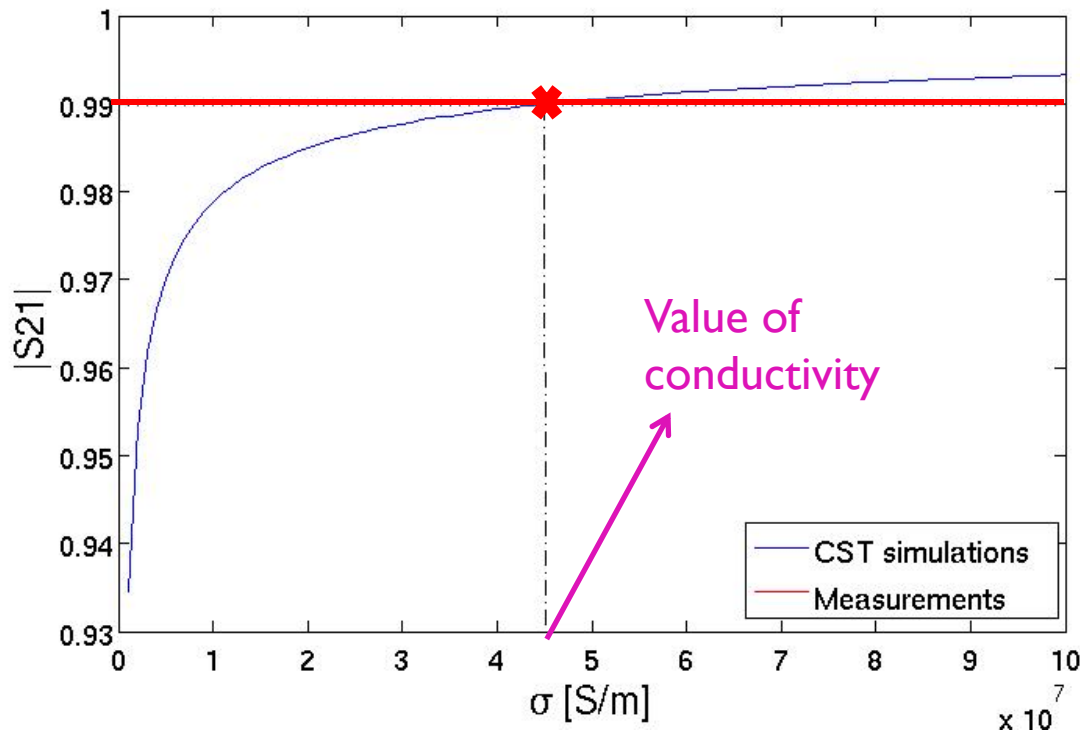
- ▶ Software package for electromagnetic field simulations
- ▶ The tool Transient Solver also delivers as results the S-parameters
- ▶ CST is used to simulate the Cu waveguide (same dimensions as the ones used in the experiment → simulating the experimental setup)

*X band Cu waveguide
simulated with CST MWS*



3D EM Simulations and measurements (I)

- ▶ X band Cu waveguide, $\epsilon_r = \mu_r = 1$, σ is the (unknown) scanned parameter
- ▶ For each frequency from 9-12 GHz, the output result is the S_{21} coefficient as a function of conductivity
- ▶ Combine with the measurement results $\rightarrow \sigma$ as a function of frequency



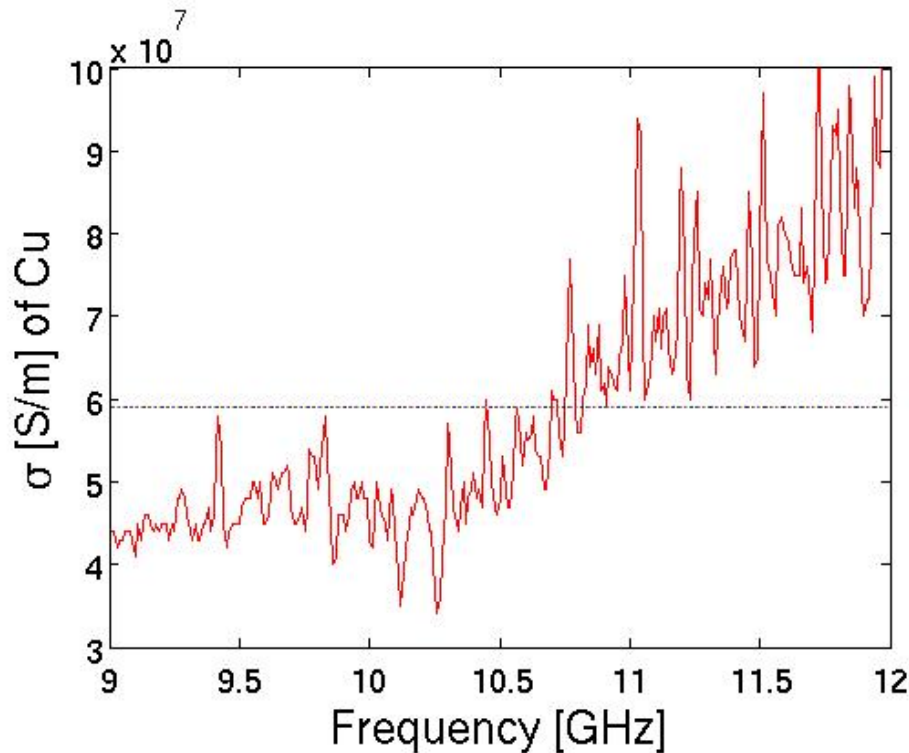
Example at 10 GHz

Intersection of the simulation results with the measurement \rightarrow point of intersection defines the conductivity

3D EM Simulations and measurements (II)

Conductivity of Cu

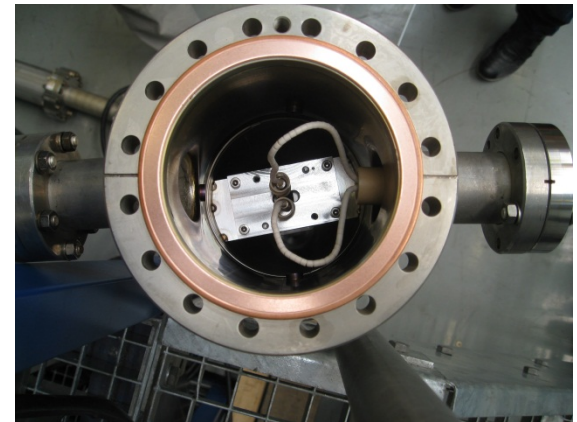
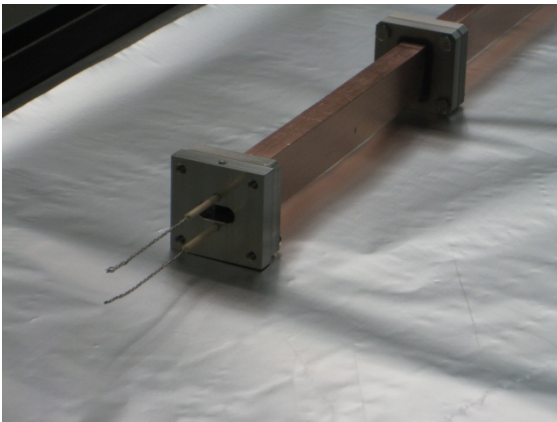
- ▶ Result from the intersection of measurements with CST MWS simulations



- Cu conductivity was estimated within the same order of magnitude with the known value
- Average is 5.91×10^7 S/m
- Good agreement with the known value of 5.8×10^7 S/m
- The attenuation is very sensitive to the errors because of the small losses (high conductivity of Cu)
- Despite this, the results were encouraging to continue with a coated waveguide

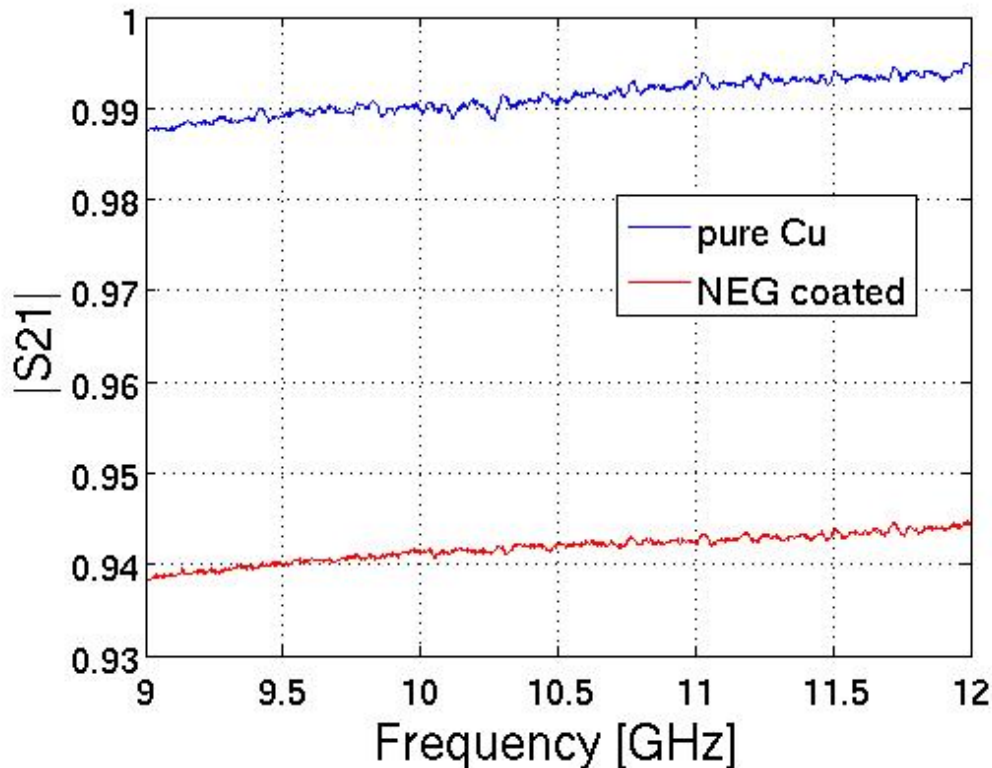
Experimental Method (III)

- ▶ NEG coated Cu waveguide
 - ▶ Same Cu waveguide used before is now coated with NEG
- ▶ Coating procedure
 - ▶ Elemental wires intertwined together produce a thin Ti-Zr-V film by magnetron sputtering
 - ▶ Coating was targeted to be as thick as possible (9 μm from first x-rays results)



Experimental Method (IV)

- ▶ NEG coated Cu waveguide
 - ▶ Measure the S_{21} from 9-12 GHz



- S_{21} results indicate that the skin depth is small enough compared to the coating thickness
- Allows the EM interaction with the NEG

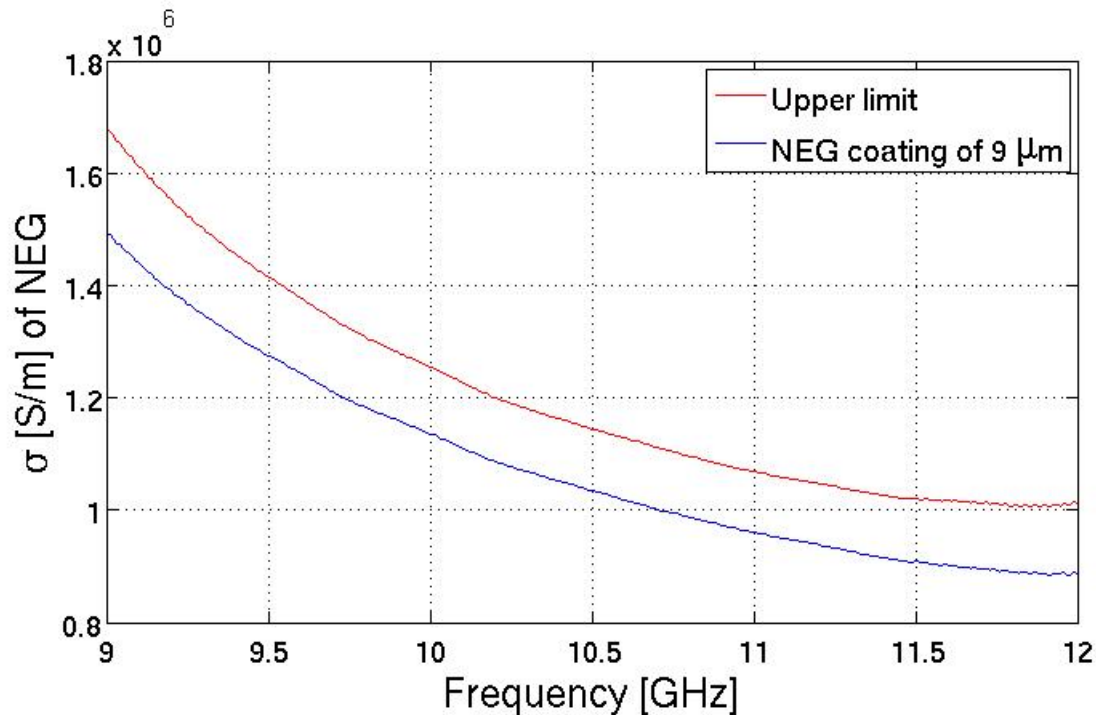
3D EM Simulations and measurements (III)

Conductivity of NEG

- ▶ Real thickness profile → unknown
- ▶ First indication from x-rays
- ▶ 2 scenarios
 - ▶ skin depth \ll thickness → losses only from NEG → σ_{NEG}
 - ▶ simulation: infinite thickness of NEG → upper limit
 - ▶ skin depth \sim thickness → losses from NEG and Cu → σ_{NEG}
 - ▶ simulation: NEG-coated (9 μm) Cu waveguide

3D EM Simulations and measurements (IV)

Conductivity of NEG



- Upper limit for the conductivity of NEG in this frequency range
- Preliminary results

- Errors
 - Experimental method (stainless steel waveguide)
 - Benchmark CST MWS coating simulations

First tests of the CST MWS simulations (I)

- ▶ Check the results reliability of coating simulations
- ▶ First tests

Compare simulations

1. A Cu waveguide NEG coated of 100 μm (2 materials)

- Assuming $\sigma_{\text{NEG}} = 2 \times 10^6$ S/m, the skin depth is varying from 3.9-3.2 μm for 8-12 GHz

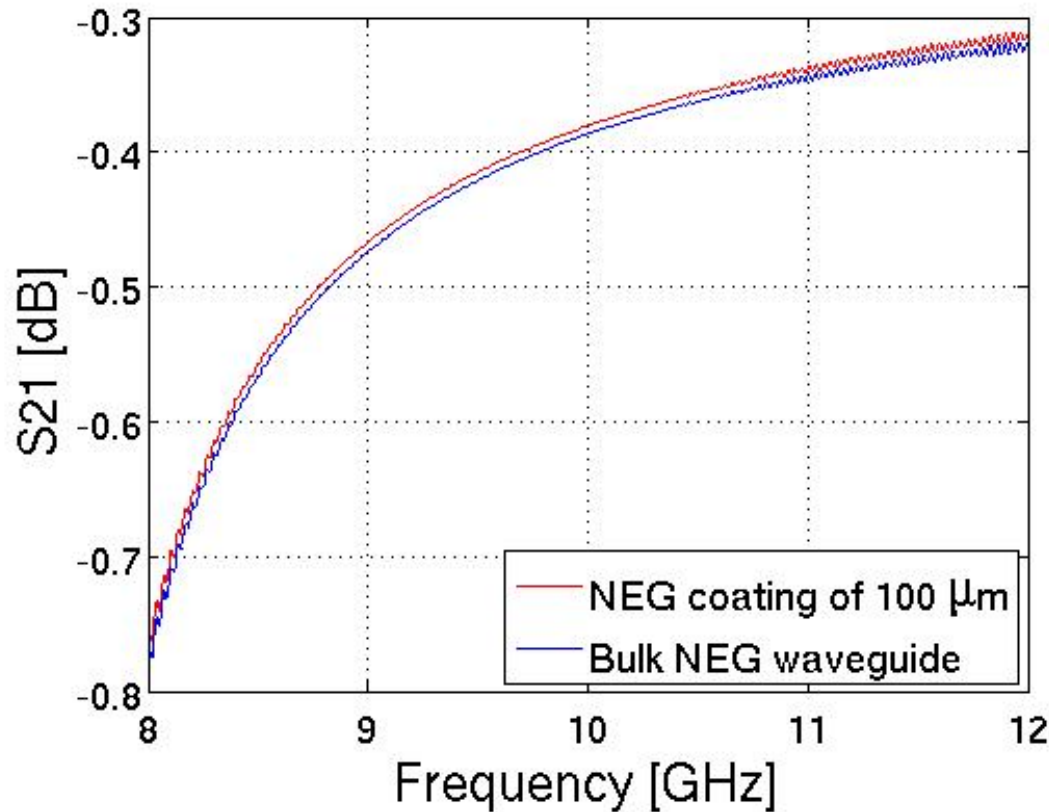
$$\delta = \sqrt{\frac{2}{\mu\omega\sigma}} \approx 503 \sqrt{\frac{1}{\mu_r f \sigma}}$$

- skin depth \ll 100 μm thickness \rightarrow EM interaction only with NEG

2. A waveguide from NEG (1 material)

First tests of the CST MWS simulations (II)

- ▶ Compare the results from simulations for the 2 cases



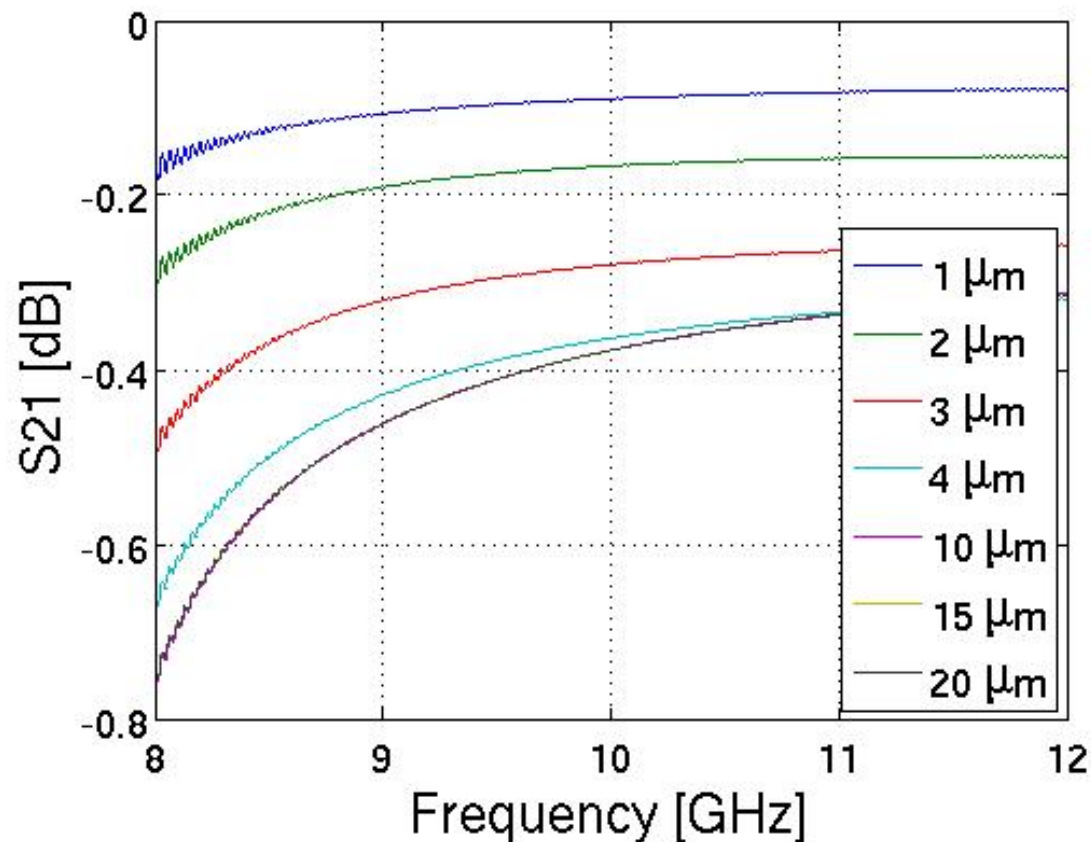
The results are in a very good agreement, 1% error

First tests of the CST MWS simulations (III)

- Simulate different values of NEG thickness and check the output of simulations
 - From 8-12 GHz, skin depth varies from 3.9-3.2 μm ($\sigma_{\text{NEG}} = 2 \times 10^6 \text{ S/m}$)
 - Simulate thickness from 1-20 μm

First tests of the CST MWS simulations (IV)

- ▶ Compare results for different NEG thickness from 1-20 μm

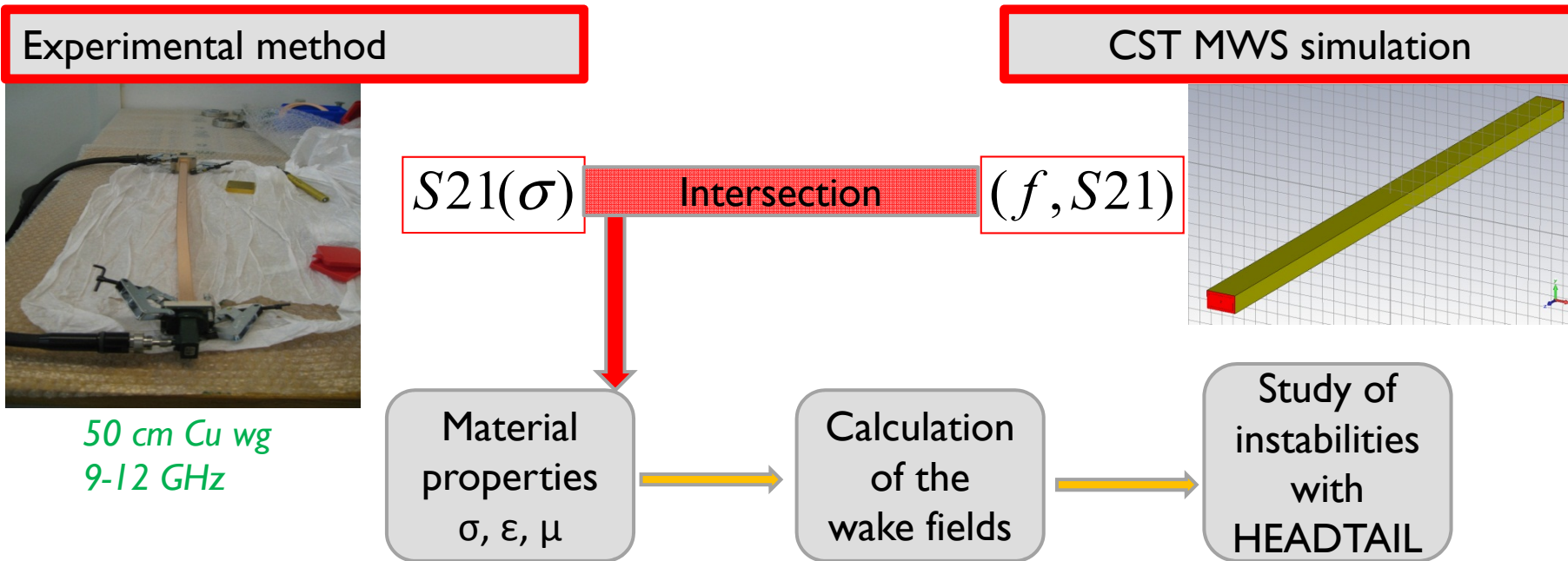


- For small values, 1-4 μm , the skin depth is larger or comparable to the thickness \rightarrow small losses due to Cu
- For 10-20 μm , the skin depth \ll thickness \rightarrow higher losses due to NEG

The results are in agreement with the expected ones

Summary

- ⇒ NEG (Non Evaporable Getter)/ aC (amorphous Carbon) coating is necessary for good vacuum and to fight e^- cloud in the EDR and PDR of CLIC
- ⇒ Unknown material properties at high frequencies
- ⇒ Combine experimental results with CST simulations
- ⇒ Powerful tool for this kind of measurements

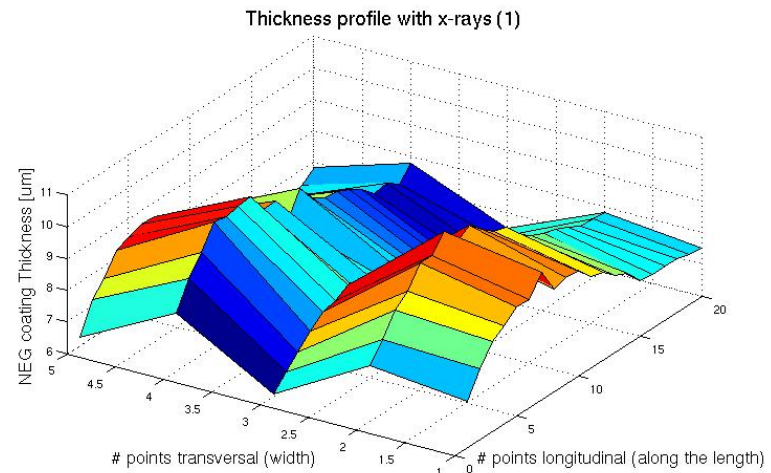


Conclusions- Future work

- ⇒ The waveguide method combined with CST EM simulations was tested at frequencies from 9-12 GHz for a Cu NEG coated waveguide
- ⇒ The results were encouraging
- ⇒ Upper limit for the NEG conductivity at this frequency range
- ⇒ Measurements for a stainless steel waveguide will take place (error of the method)
- ⇒ CST MWS simulations will be benchmarked (error of simulations)
- ⇒ Measurements on a different coating? aC?

Challenges...

- ▶ Measure properties at high frequencies...
 - Up to 500 GHz/ 500 GHz Network analyzer (EPFL)
 - Very short waveguides, Y-band (0.5 x 0.25 mm)
- ▶ Challenges
 - Manufacture of the small waveguide
 - Coating technique
 - Profile measurements
- ▶ Simulation
 - Non-uniform coating



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Thank you for your attention!